# Monthly LabAdviser update: 28/9 2016

|  |  |  |
| --- | --- | --- |
| Updated Subject  | Contributor | Link to the updated pages |
| **Sputter coater 03**New sputter coater in the basement for use before SEM  | **Pernille V. Larsen @danchip** | [Sputter\_coater#Sputter\_coater\_03](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Sputter_coater#Sputter_coater_03) |
| **ALD**Standard recipe page updated:TiO2 processes add and Al2O3 updated. | **Pernille V. Larsen****@danchip** | [ALD\_Picosun\_R200/Standard\_recipes\_on\_the\_ALD\_tool](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/ALD_Picosun_R200/Standard_recipes_on_the_ALD_tool) |
| **Equipment to be decommissioned**This can no longer be found in LabAdviser. This is to be found on LabManager “Main” page. | **Thøger Eskildsen @danchip** | <http://labmanager.dtu.dk/function.php?module=Machine&view=currentinfo#decom> |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

|  |
| --- |
|  |

|  |
| --- |
|  |

|  |  |  |
| --- | --- | --- |
|

|  |
| --- |
|  |

|  |
| --- |
|  |

 |
|  |
|  |
|  |
|  |

|  |
| --- |
|  |

|  |  |
| --- | --- |
|  | * APV and manual for Extraction box to prepare nano particles
 |
|  | * Manual for Plasma Asher1\_Model 300 Plasma Processor
 |
|  | * Manual for KS Aligner\_MA6
 |
|  | * Manual for Developer: TMAH Manual
 |
|  | * Manual for Sputter system (LESKER)
 |
|  | * Manual for LPCVD Poly Silicon Furnace (6") (E2)
 |
|  | * Manual for Sputter Coater 03
 |
|  | * Manual for Anneal Oxide furnace (C1)
 |
|  | * Manual for BCB Curing Oven
 |
|  | * Manual for III-V oxide furnace
 |

|  |
| --- |
|  |

|  |
| --- |
|  |